

INFORMATION DISCLOSURE CITATION IN AN APPLICATION				Docket Number		Application Number	
				M4065.0139/P139-A		Not Yet Assigned	
				Applicant(s)			
				Cem Basceri			
				Filing Date		Group Art Unit	
August 4, 2000		2812					
U.S. PATENT DOCUMENTS							
*EXAMINER INITIAL	REF	DOCUMENT NO.	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
EL	A	5,618,761	04/1997	EGUICH et al.			
EL	B	5,453,908	09/1995	TSU et al.			
FOREIGN PATENT DOCUMENTS							
	REF	DOCUMENT NO.	DATE	COUNTRY	CLASS	SUBCLASS	Translations YES NO
EL	C	0 380 326	08/1990	EPO			
OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)							
EL		H. Yamawaki et al., "ULTRA THIN $\text{SrBi}_2\text{Ta}_2\text{O}_9$ FERROELECTRIC FILMS GROWN BY LIQUID SOURCE CVD USING BiOx BUFFER LAYERS" Abstracts of the 1998 International Conference on Solid State Devices and Materials, Hiroshima, 1998, pages 102-103.					
	D						

EXAMINER	DATE CONSIDERED
H. Tsai	4/16/01
EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP Section 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to Applicant.	